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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**
(Use as many sheets as necessary)

Complete if Known	
Application Number	Unknown
Filing Date	Even Date Herewith
First Named Inventor	Ahn, Kie
Group Art Unit	Unknown
Examiner Name	Unknown
Attorney Docket No: 303.686US3	

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Andy Nayak

DATE CONSIDERED

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Information Disclosure Statement Form (PTO-1448)

*EXAMINER: Initial or reference considered, whether or not stated in conformance with 37 CFR 1.56. Draw a through slash if not in conformance and not considered. Include copy of this form with next communication to applicant. *Applicant's unique docket designation number (optional) *Applicant is to place a check mark here if English language Translation is attached



Information Disclosure Statement Form (PTO-1448)

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**
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Complete if Known						
Application Number		Unknown				
Filing Date		Even Date Herewith				
First Named Inventor		Ahn, Kie				
Group Art Unit		Unknown				
Examiner Name		Unknown				
Attorney Docket No: 303.686US3						
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* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 804. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication if applicant's unique citation designation number (if any) is placed to place a check mark here if English language Translation is attached